

Atomic Layer Deposition of SnO₂ as an Electron Transport Material for Solid-State P-type Dye-Sensitized Solar Cells

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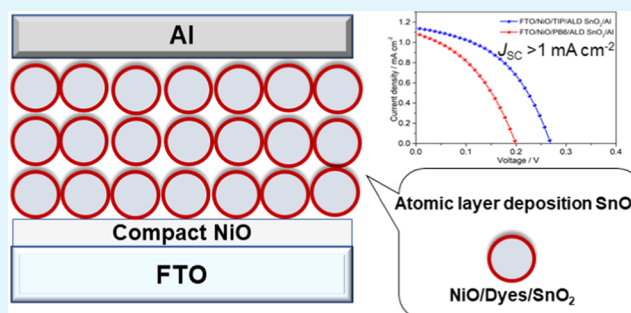
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Supporting Information

ABSTRACT: Tin oxide (SnO₂) as an electron transport material was prepared by atomic layer deposition in dye-sensitized NiO films to fabricate solid-state p-type dye-sensitized solar cells using two organic dyes PB6 and TIP as photosensitizers. Due to the excellent electron mobility and satisfactory penetration of SnO₂ material into the NiO film, a record photocurrent density over 1 mA cm⁻² was achieved with a power conversion efficiency of 0.14%. The effect of an inserted Al₂O₃ layer between the dye-sensitized NiO and SnO₂ layer on photovoltaic performance of the devices was also investigated. The results suggest that the charge recombination between NiO and SnO₂ can be significantly suppressed, showing prolonged charge lifetime and enhanced photovoltage.

KEYWORDS: atomic layer deposition, electron transport materials, high current density, p-type DSSCs, tin oxide



INTRODUCTION

Since the report of pioneer work by O'Regan and Grätzel and co-authors in 1991,¹ dye-sensitized solar cells (DSSCs) have attracted great attention.² The traditional DSSCs, also called n-type DSSCs, are based on dye-sensitized TiO₂ photoanodes, which have experienced rapid progress during the past three decades.^{3,4} In 1999, Lindquist and co-authors reported p-type DSSCs with a liquid electrolyte in which dye-sensitized NiO films were used as a photocathode.⁵ The photocathode plays a vital role in tandem DSSCs, which could reach a theoretical power conversion efficiency (PCE) of more than 30%. However, the development of p-type DSSCs is still far behind that of n-type DSSCs.⁶ Various studies have been focused on improving the performance of p-type DSSCs^{7–11} because of their good potential in tandem solar cells and solar fuel devices.^{12,13}

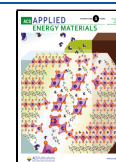
The traditional liquid p-type DSSCs consist of a dye-sensitized mesoporous NiO photocathode, an I⁻/I₃⁻ redox couple, and a counter electrode. Due to the small energy difference between the valence band (VB) of NiO and reduction potential of I⁻/I₃⁻, the open-circuit voltage (V_{oc}) of p-type DSSCs is normally very low, less than 200 mV.^{14,15} In addition, the severe charge recombination in liquid p-type DSSCs also leads to the low V_{oc} and poor fill factor (FF).^{16,17} Moreover, the stability of the liquid device due to potential electrolyte leaking is always a concern. Besides the good stability, the solid-state p-type DSSCs can achieve high voltage because of high energy difference between the VB of NiO and

the conduction band (CB) of electron transport material (ETM). In 2014, our group¹⁸ reported the first example of solid-state p-type DSSCs using P1 dye as a photosensitizer and PCBM as ETM, which achieved a V_{oc} of 620 mV. A slow charge recombination between holes in NiO and electrons in PCBM⁻ was observed. However, the photocurrent density (J_{sc}, 50 μA cm⁻²) of such a device was extremely low because of the low electron mobility and thick layer of PCBM. Other diketopyrrolopyrrole derivatives have also been used in the PCBM-based solid-state p-type DSSCs, showing an enhanced J_{sc} of 0.45 mA cm⁻² because of their strongly reducing ability and long lifetime of the charge-separated state.¹⁹ Subsequently, our group employed inorganic metal oxides (TiO₂ and ZnO) with high electron mobility as ETM.^{20–23} Atomic layer deposition (ALD) of TiO₂ has been proved to be able to enhance ultrafast charge separation and dye regeneration (t_{1/2} ≤ 500 fs) in a core-shell NiO-dye-TiO₂ film.²¹ Although the photocurrent density of the solar cell using ZnO as ETM has made a big improvement,²³ the J_{sc} of solid-state p-type DSSCs was still lower than 1 mA cm⁻², which was much lower than that of liquid p-type DSSCs. According to our previous study,

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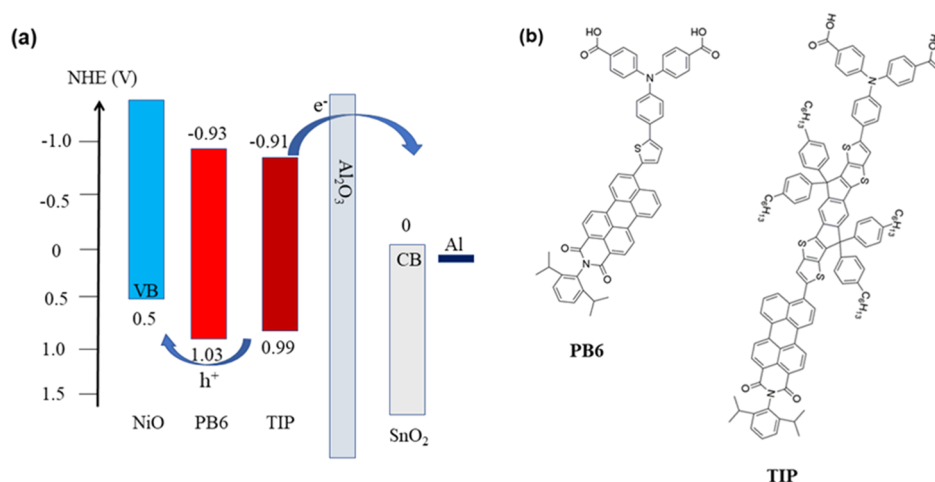


Figure 1. (a) Energy levels of components used in p-type solid-state DSSCs with ALD SnO_2 as ETM. (b) Molecular structures of PB6 and TIP dyes.

the fact that a majority of dyes are not entirely electrically connected with the ETM contributes to the low J_{sc} of solid-state p-type DSSCs.²⁴ These results encouraged us to further explore other suitable metal oxides as ETMs and improve photovoltaic parameters.²⁵

Tin oxide (SnO_2) is an n-type metal oxide semiconductor with high electron mobility and stability, which has been used as ETM in perovskite solar cells.^{26,27} Its electron mobility can reach as high as $410 \text{ cm}^2 \text{ V}^{-1} \text{ s}^{-1}$.²⁸ In this work, we employed SnO_2 as ETM in solid-state p-type DSSCs. To make good penetration of SnO_2 into dye-sensitized NiO films, the ALD method was employed. By extending the exposure and purge time in the process of ALD of SnO_2 , good contact between dye-sensitized mesoporous NiO films and SnO_2 can be achieved, which is helpful for efficiently extracting electrons from the dyes after hole injection into NiO. A record J_{sc} over 1 mA cm^{-2} was reached for solid-state p-type DSSCs. In addition, introduction of ALD Al_2O_3 between the dye-sensitized NiO and SnO_2 layer can suppress the charge recombination, resulting in an obvious enhancement of the photovoltage.

EXPERIMENTAL SECTION

Materials. PB6²¹ and TIP²³ dyes were reported in our previous work. Fluorine-doped tin-oxide coated glass (FTO, TEC15) was purchased from Pilkington. *tert*-Butanol, acetonitrile, zinc powder, and hydrochloric were purchased from Sigma-Aldrich. Aluminum (Al) wire was purchased from Umicore.

Device Fabrication. The FTO conductive glass substrates were etched with 2 M hydrochloric and zinc powder. The etched FTO substrates were washed with detergents, deionized water, acetone, and ethanol using an ultrasonic bath. Then, the cleaned FTO were dried with flow N_2 . A compact NiO blocking layer (80 nm) was deposited on the FTO substrate by reactive magnetron sputtering. The deposition condition is the same as our previous work.²¹ Before screen printing the mesoporous NiO film, the sputtered NiO blocking layer was annealed in an oven at 450°C for 0.5 h in an ambient atmosphere. The NiO paste was prepared according to the previous literature.²² Then, one layer of mesoporous NiO films with a thickness of 750 nm was deposited on the blocking layer by the screen printing method. The screen-printed NiO film was transferred into an oven and sintered at 450°C for 30 min. After cooling to room temperature, the mesoporous NiO films were dipped into a 0.2 mM dye (PB6 or TIP) *tert*-butanol/acetonitrile ($v/v = 1:1$) solution for 16 h. Subsequently, the sensitized NiO film was rinsed with ethanol and

dried with N_2 flow. The ETM SnO_2 was deposited in the NiO film by the ALD method. The back-contact (Al) electrode was deposited on the ALD SnO_2 film with a thickness of 120 nm. For NiO/dye/ Al_2O_3 / SnO_2 -based devices, the point Al_2O_3 was inserted after NiO sensitization but before ALD of SnO_2 .

ALD of Al_2O_3 and SnO_2 . The ALD employed a stop-flow process in the project. The precursors for ALD of Al_2O_3 were composed of trimethylaluminum (TMA) and deionized water (H_2O). The temperature of the chamber was 120°C with a stability time of 1 h before the ALD process. In total, 10 cycles of Al_2O_3 were deposited on the NiO film.

The stop flow involved a sequence of (1) reduced carrier gas flow, (2) reduced pumping speed through a bypass constriction, (3) precursor injection, (4) precursor exposure, (5) restored pumping speed, and (6) restored carrier gas flow and purging. For the TMA precursor, the duration of steps 1 to 6 were 2, 2, 0.2, 21.8, 2, and 2 s. During this sequence, the carrier gas flow was reduced from 40 to 10 standard cubic centimeters per minute (sccm) in each of the five unused precursor lines of the system. The TMA line used a flow of 150 sccm during the injection step. In the H_2O half-cycle, the duration of steps 1 to 6 was the same, that is, 2, 2, 0.2, 21.8, 2, and 2 s, while the H_2O carrier gas flow was increased to 150 sccm and the other precursor line flows were reduced to 10 sccm.

The precursor of ALD SnO_2 was composed of tetrakis-(dimethylamido)tin (TDMASn) and deionized water (H_2O) and used the same stop-flow time sequence as for the Al_2O_3 ALD. The carrier gas (N_2) flow was 200 and 200 sccm during the TDMASn and H_2O injection steps, respectively. In all, 100 cycles of SnO_2 were deposited on the NiO film. A slide of Si wafers was used to evaluate the thickness of SnO_2 and Al_2O_3 with a spectroscopic ellipsometer.

Device Characterization. The sputtering of NiO films was performed on a Von Ardenne magnetron sputter system (CS730S) with a Ni target. The ALD was performed on a new PICOSUN R-200 advanced ALD system. The back-contact layer (Al) was deposited on a Lesker PVD 75 evaporator. Current density–voltage (J – V) curves were measured using a Newport solar simulator (model 91160, AM 1.5 G) equipped with a Keithley 2400 source meter. Before measurement, the light intensity (100 mW cm^{-2}) was calibrated with a calibrated filter Si cell. The area of the mask was 0.125 cm^2 during the measurement. The incident photon-to-current efficiency (IPCE) spectrum was measured with a setup consisting of a xenon lamp (Spectral Products ASB-XE-175), a monochromator (Spectral Products CM110), and a Labjack U6 DAQ board. The IPCE device was calibrated with a Si solar cell before measurement.

Transient Photocurrent and Photovoltage Measurements. The transient photocurrent and photovoltage measurements were conducted using a Dynameo tool-box DN-AE01 system. The light intensity (white LED light, Luxeon Star 1 W) was adjusted by

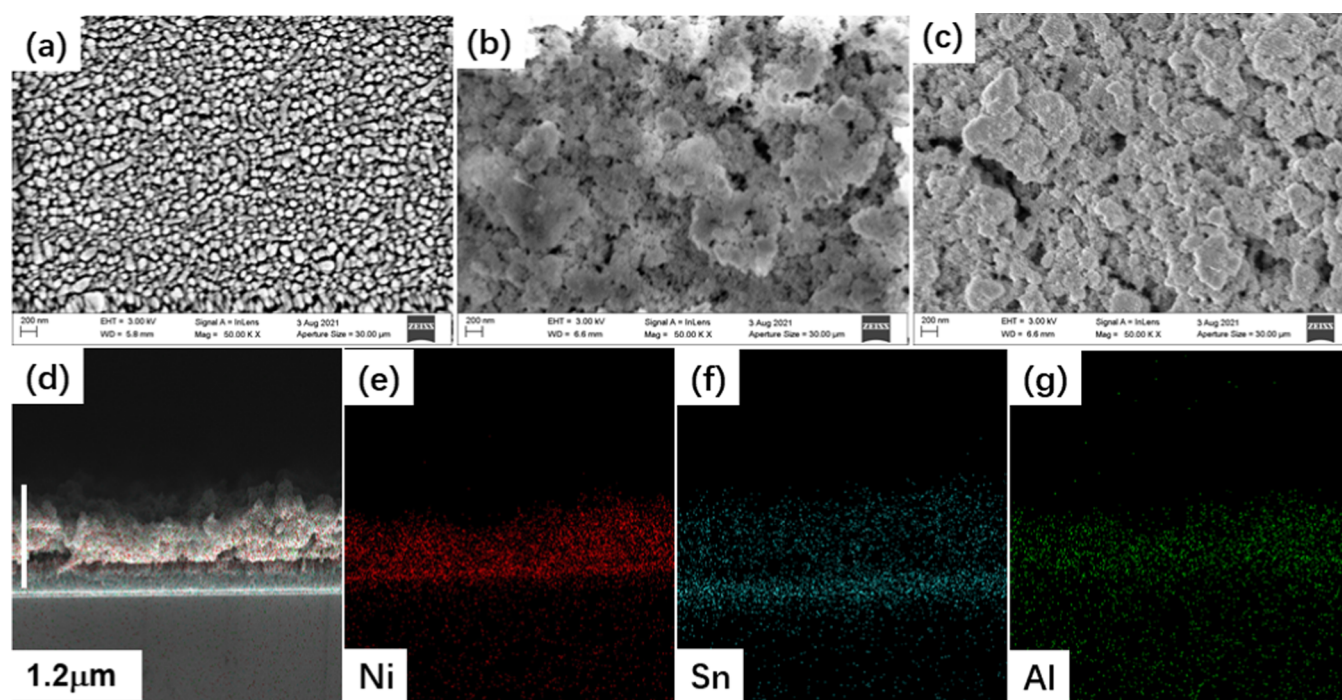


Figure 2. (a) SEM image of the sputter-deposited NiO blocking layer on the FTO substrate, (b) SEM image of mesoporous NiO films; (c) SEM image of atomic layer-deposited SnO₂ film on the FTO/NiO film; (d) cross-section SEM image of FTO/NiO/PB6/ALD Al₂O₃/ALD SnO₂; and (e–g) EDX element mapping of Ni, Sn, and Al.

changing the applied voltage. The charge lifetime and charge transport lifetime were achieved by fitting the decay of the transient photocurrent and transient photovoltage, respectively.

RESULTS AND DISCUSSION

The device structure of the solid-state p-type DSSCs, which is composed of electrodes (FTO/NiO), dyes (PB6 or TIP), ETM (ALD SnO₂), and back-contact material (Al), is shown in Figure 1. The energy levels of components used in solid-state p-type DSSCs are illustrated in Figure 1a. Under light illumination, the excited dye injects hole into the NiO VB, and then, the reduced dye injects electron into the SnO₂ CB. Two dyes, PB6 and TIP, with a D- π -A structure (Figure 1b), but different in the π linkers, are used as the photosensitizers. The energy levels of NiO, dyes, and Al₂O₃ are taken from our previous work.^{20,23} For SnO₂, the energy levels are taken from the literature,²⁹ which has used a similar method to prepare ALD SnO₂.

The detailed process of ALD of SnO₂ into mesoporous NiO films is shown in Figure S1. According to our previous work,²⁰ the good core–shell structure of NiO and ALD TiO₂ can show ultrafast hole and electron injection, which is beneficial for the dye regeneration. In order to have good penetration of SnO₂ into the mesoporous NiO film, an extended precursor exposure time was applied in this work (see details in the Experimental Section). The process of ALD of Al₂O₃ is similar to ALD of SnO₂.

In order to observe the morphology of the films and check the status of SnO₂ penetration, scanning electron microscopy (SEM) is used to characterize the morphology of different layers. The SEM image of the sputter-deposited NiO blocking layer film is shown in Figure 2a. One can see a very dense and uniform NiO film, which is beneficial to effectively block the unwanted contact between FTO and SnO₂, avoiding short circuit from the contact of the back-contact and FTO surface.

Figure 2b displays the SEM image of the mesoporous NiO film that is helpful for loading more dyes. After 100 cycles of ALD of SnO₂ (about 16 nm) layers into the mesoporous NiO film, the morphology of the NiO/ALD SnO₂ film still remains porous from the SEM image in Figure 2c but becomes denser. In order to check if the ALD SnO₂ and Al₂O₃ have good penetration into the mesoporous NiO film, energy-dispersive X-ray spectroscopy (EDX) of the cross-section SEM image (Figure 2d) of FTO/NiO/Al₂O₃/SnO₂ has been carried out. The result shows a uniform distribution of SnO₂ in the mesoporous film, indicating good penetration of ALD SnO₂ into the NiO film. Due to the presence of Sn in the FTO substrate, Sn can be also observed in the part of FTO in Figure 2f. The uniform distribution of Al₂O₃ in the mesoporous NiO film indicates better penetration than that in our previous work,²⁰ likely due to longer exposure time in the process of ALD.

A more intimate contact between SnO₂ and NiO (near to dye) can not only promote charge separation but also increase charge recombination, while use of a thin Al₂O₃ layer can suppress such charge recombination. From our previous study,²⁰ a thin ALD Al₂O₃ layer between dye and NiO did not influence the hole injection and a thin ALD Al₂O₃ layer between NiO and ETM did not influence fast electron injection from the dye to ETM. In this work, we sensitized dye first and then used ALD Al₂O₃, so the electronic coupling between NiO and the dye should not be significantly changed. The satisfactory penetration of SnO₂ and Al₂O₃ into mesoporous NiO films is therefore expected to accelerate charge separation and suppress charge recombination, thereby benefitting photovoltaic parameters.

To evaluate the photovoltaic performance of the solid-state p-type DSSCs, two kinds of devices, with or without Al₂O₃ layers, were assembled. For the device of FTO/NiO/dyes/SnO₂/Al, the photocurrent density–photovoltage (J – V)

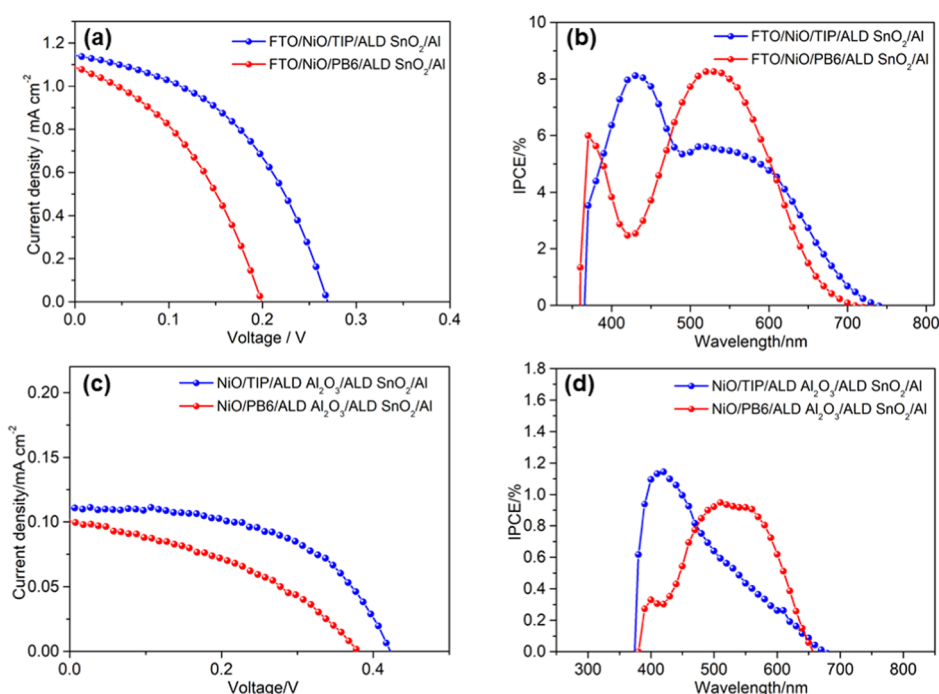


Figure 3. (a) Photocurrent density–photovoltage (J – V) curve and (b) IPCE spectra of FTO/NiO/PB6- and TIP/ALD SnO_2 /Al-based devices and (c) photocurrent density–photovoltage (J – V) curve and (d) IPCE spectra of FTO/NiO/PB6- and TIP/ALD Al_2O_3 /ALD SnO_2 /Al-based devices (the thickness of Al_2O_3 and SnO_2 is 1 and 16 nm, respectively).

Table 1. Photovoltaic Parameters of Solid-State p-Type DSSCs (Light Intensity: AM 1.5G, 100 mW cm^{-2} ; Active Area: 0.125 cm^2)

Device	V_{oc} (V)	J_{sc} (mA cm^{-2})	FF	PCE (%)
FTO/NiO/PB6/ SnO_2 /Al	0.199	1.082	0.397	0.086
FTO/NiO/TIP/ SnO_2 /Al	0.269	1.140	0.458	0.141
FTO/NiO/PB6/ Al_2O_3 / SnO_2 /Al	0.381	0.100	0.392	0.015
FTO/NiO/TIP/ Al_2O_3 / SnO_2 /Al	0.423	0.110	0.541	0.025

curves are shown in Figure 3a and their photovoltaic parameters are listed in Table 1. A PCE of 0.086% was achieved with a V_{oc} of 0.199 V, a J_{sc} of 1.082 mA cm^{-2} , and a FF of 0.397 when PB6 dye was used in the device. Using TIP dye instead of PB6 dye, the FTO/NiO/TIP/ SnO_2 /Al-based device reached a PCE of 0.141% with a V_{oc} of 0.269 V, a J_{sc} of 1.141 mA cm^{-2} , and a FF of 0.458. The J_{sc} of the FTO/NiO/TIP/ SnO_2 /Al-based device is a record for the solid-state p-type DSSCs. When the dyes were varied in FTO/NiO/dyes/ SnO_2 /Al-based devices, the TIP dye-based device attained higher V_{oc} and FF values than those of the PB6 dye-based device. Such results can be attributed to the π bridge in TIP dye having a stronger ability to suppress the charge recombination between holes in the NiO VB and electrons in the SnO_2 CB in the solar cell than the PB6 dye does. The IPCE spectra of FTO/NiO/dyes/ SnO_2 /Al-based devices are shown in Figure 3b. The maximum value of IPCE is beyond 8%, which is a big progress for solid-state p-type DSSCs. Although the J_{sc} values of FTO/NiO/dyes/ SnO_2 /Al-based devices are largely improved, the V_{oc} of such devices is still lower than what we reported previously using other metal oxides as ETMs.^{20,22} The positive CB of SnO_2 and unwanted charge recombination may contribute to the low V_{oc} . To suppress the charge recombination, an ALD Al_2O_3 layer with 10 cycles (about 1 nm) was deposited on the NiO/dyes film prior to ALD of SnO_2 to form the FTO/NiO/dyes/ Al_2O_3 /

SnO_2 /Al-based device. For the FTO/NiO/PB6/ Al_2O_3 / SnO_2 /Al-based device (Figure 3c), a V_{oc} of 0.381 V was reached, which is much higher than that of the FTO/NiO/PB6/ SnO_2 /Al-based ($V_{oc} = 0.199 \text{ V}$) device without Al_2O_3 . A similar phenomenon can be observed for the TIP dye-based device, which achieved a V_{oc} of 0.423 V with Al_2O_3 in the device. The theoretical photovoltage of the device based on SnO_2 ETM is 0.5 V determined from the potential difference between the VB of NiO and the CB of SnO_2 . These results indicate that the ALD of Al_2O_3 can effectively suppress the charge recombination and therefore enhance the V_{oc} of solid-state p-type DSSCs. In addition, the FF (0.541) of the TIP dye-based device is also enhanced. However, the J_{sc} of the FTO/NiO/dyes/ Al_2O_3 / SnO_2 /Al-based device is much lower than that of the device without Al_2O_3 , and the maximum IPCE (Figure 3d) value of FTO/NiO/dyes/ Al_2O_3 / SnO_2 /Al is reduced to about 1%. In our previous work,²⁰ we did not observe that the hole injection from the dye was significantly affected by introduction of a thick Al_2O_3 layer.

In our previous work, we found that the electron injection from the reduced dye to NiO surface states is an interface charge transfer pathway.³⁰ Considering the energy levels of NiO surface states (ca. +0.6 to −0.4 vs NHE) and SnO_2 CB (0 vs NHE), the electron transfer from the injected electrons in NiO surface states to the SnO_2 CB is also thermodynamically feasible. Therefore, besides direct electron injection from the

reduced dye to SnO_2 , the electron injection via NiO surface states to SnO_2 could be another pathway. However, when one cycle of Al_2O_3 is applied to passivate the majority of the NiO surface states, the direct electron transfer from the reduced dye to SnO_2 should dominate the charge separation process. A mechanism scheme of interface charge separation is shown in Figure 4. In addition, the conductivity of the NiO film is

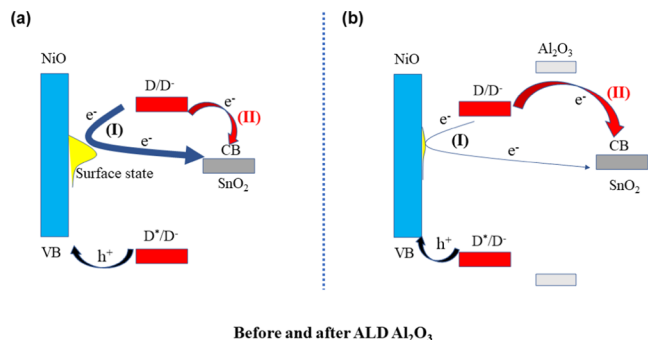


Figure 4. Possible process of electron transfer before and after ALD of Al_2O_3 .

decreased obviously after inserting Al_2O_3 ,³⁰ which could have a negative effect on the J_{sc} as well. The reduced J_{sc} could be therefore explained by the removal of NiO surface states by Al_2O_3 which influences interface charge transfer and the hole transport in NiO films.³⁰

To elucidate the variation of V_{oc} and J_{sc} after ALD of Al_2O_3 , transient photovoltage/photocurrent techniques are used to analyze the process of charge transport. The relation between charge lifetime and photovoltage is shown in Figure 5a. The V_{oc} is adjusted with different light intensities. As shown in Figure 5a, the FTO/NiO/PB6/ Al_2O_3 / SnO_2 /Al-based device has a much longer charge lifetime than that of the FTO/NiO/PB6/ SnO_2 /Al-based device, which suggests that inserting Al_2O_3 into the device can effectively suppress the charge recombination and then improve photovoltage of the device.^{24,30} The same trend can be observed in Figure 5a for the TIP dye-based device. In addition, the charge lifetime of FTO/NiO/TIP/ Al_2O_3 / SnO_2 /Al is longer than that of the FTO/NiO/PB6/ Al_2O_3 / SnO_2 /Al-based device. These results indicate that the TIP dye with indacenodithieno[3,2-*b*]-thiophene as a π linker has a stronger ability in suppressing the charge recombination than the PB6 dye with thiophene as a π linker.²³ As a result, the TIP dye-based device can reach

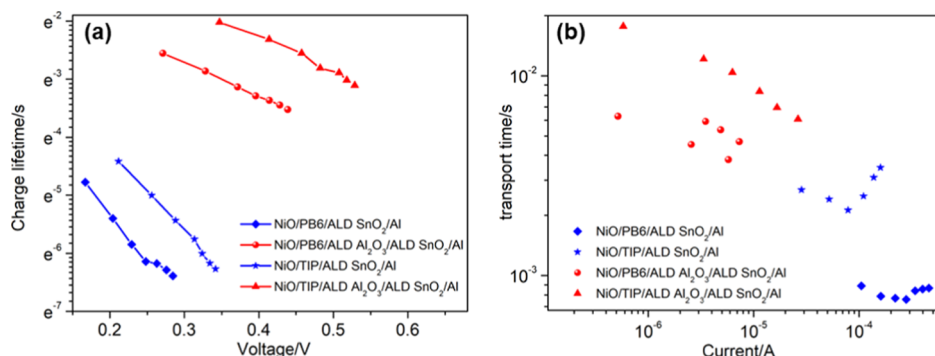


Figure 5. (a) Relation between charge lifetime and voltage for NiO/dye/ SnO_2 /Al- and NiO/dye/ Al_2O_3 / SnO_2 /Al-based devices and (b) relation of charge transport time with current.

higher V_{oc} than that of the PB6 dye-based device under the same condition (with or without Al_2O_3), which is consistent with previous reports.^{23,31} To explain why the FTO/NiO/dyes/ SnO_2 /Al-based device has a much higher J_{sc} than the FTO/NiO/dyes/ Al_2O_3 / SnO_2 /Al-based device, the dependence of charge transport time on photocurrent is measured.^{32,33} As displayed in Figure 5b, the FTO/NiO/dyes/ SnO_2 /Al-based device has a much shorter charge transport time than that of the FTO/NiO/PB6/ Al_2O_3 / SnO_2 /Al-based device, which can explain the higher photocurrent density obtained from the devices without Al_2O_3 layers. After tracking the PCE of the FTO/NiO/PB6/ SnO_2 /Al-based device for above 1300 h under the air condition in dark, the device can maintain over 88% of the highest PCE (Figure S7).

To assess effects of thickness of the Al_2O_3 layer on the performance, three different thicknesses of the Al_2O_3 layer (0.1, 0.5, and 1 nm) were prepared. The J - V curve is shown in Figure 6 and the corresponding photovoltaic data are collected

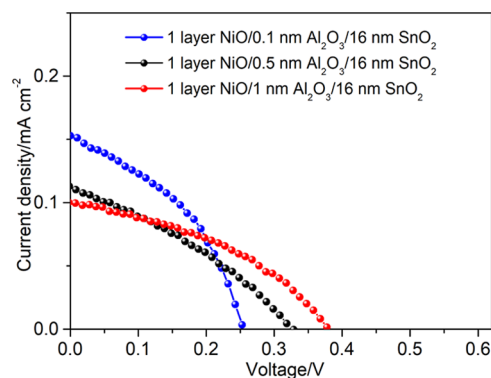


Figure 6. J - V curves of solid-state p-type DSSCs (FTO/NiO/PB6/ Al_2O_3 / SnO_2 /Al) with different thicknesses of the Al_2O_3 layer.

in Table S3. In this paper, we used the ALD method we reported³⁰ previously to remove NiO surface states. As a result, a very obvious decrease in J_{sc} is observed by inserting one cycle (0.1 nm) of Al_2O_3 because of NiO surface states, which has been suggested to be the one of hole transport channels in the previous studies.³⁴ With the increased thickness of the Al_2O_3 layer, the J_{sc} is decreased by a low degree. In our previous work, we used transient absorption spectroscopy to measure the ultrafast regeneration of the NiO/dye/ Al_2O_3 /TiO₂-based system. We found that the introduction of one cycle of Al_2O_3 did not influence the fast electron injection from dye to the

TiO₂ CB.^{20,21} Therefore, in the NiO/dye/Al₂O₃/SnO₂-based system, the electron injection in the CB of SnO₂ should be also efficient enough. However, the V_{oc} is improved with the increased thickness of Al₂O₃ due to suppression of charge recombination between the injected holes in NiO and injected electrons in SnO₂. The trend is different from our previous result when we used TiO₂ as ETM.²⁰ There could be two possibilities: (i) The ALD method we used previously in TiO₂ work did not completely remove the NiO surface states, which is evident from the charge transport time in our previous work,²⁰ where we observed that the charge transport time is constant and not dependent on light intensity. With the removal of NiO surface states, the charge transport time is dependent on light intensity as shown in Figure 5 in this work. The same trend can be also observed in our previous work with the similar ALD method.³⁰ (ii) In SnO₂-based devices, the injected electrons in NiO surface states by excited dye transfer to the SnO₂ CB play a crucial role in charge separation. Introduction of Al₂O₃ passivates the majority of NiO surface states and therefore significantly decreases J_{sc} . The decrease in NiO conductivity should be also responsible for the decreased J_{sc} . Also, according to our previous work,³⁰ the dye sensitization can protect some surface states from ALD Al₂O₃. When the thickness of Al₂O₃ is increased, the electron transfer from the protected NiO surface states to the SnO₂ CB will be slowed down, causing decreased J_{sc} . This is different from the TiO₂-based device, where the injected electrons in NiO surface states cannot be efficiently used due to more negative potential of the TiO₂ CB than that of NiO surface states. Prasittichai and Hupp reported SnO₂/Al₂O₃ in liquid-electrolyte DSSCs³⁵ and used one cycle of ALD of Al₂O₃ to passivate the SnO₂-based photoanode, which improved the V_{oc} , FF, and electron lifetime very obviously. Their result is in consistence with our result in this work.

CONCLUSIONS

In summary, SnO₂ ETM is prepared by the ALD method in a dye-sensitized mesoporous NiO film for solid-state p-type DSSCs. By extending the exposure time in the ALD process, good penetration of SnO₂ into the mesoporous NiO film can be realized, which in turn permits good contact formation with dye-sensitized NiO particles. As a result, a photocurrent density above 1 mA cm⁻² is achieved using the FTO/NiO/dyes/SnO₂/Al-based device, which is a record for the solid-state p-type DSSCs. The FTO/NiO/TIP/SnO₂/Al-based device can reach a PCE of 0.14%. In addition, introduction of Al₂O₃ into the device can largely reduce the charge recombination to enhance the V_{oc} . This work shows the potential to further improve the efficiency of solid-state p-type DSSCs by optimizing ETMs and dyes.

ASSOCIATED CONTENT

Supporting Information

The Supporting Information is available free of charge at <https://pubs.acs.org/doi/10.1021/acsaem.2c01328>.

Process of ALD; device structure; SEM; absorption of dye on NiO films; J - V curves; stability of the device; and photovoltaic parameters of solid-state p-type DSSCs (PDF)

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Notes

The authors declare no competing financial interest.

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